

#4

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE



Applicants: Ibrahim Abdulhalim, Mike Adel, Michael Friedmann and Michael Faeyrman
Assignee: KLA-Tencor Corporation
Title: Periodic Patterns and Technique to Control Misalignment (As Amended)
Serial No.: 09/833,084 Filing Date: April 10, 2001
Docket No.: 11547 M-10703 US

San Francisco, California
October 12, 2001

COMMISSIONER FOR PATENTS
Washington, D.C. 20231

**INFORMATION DISCLOSURE STATEMENT
UNDER 37 CFR § 1.97(b)**

Dear Sir:

Pursuant to 37 C.F.R. § 1.56, § 1.97 and § 1.98, the documents listed on the accompanying form PTO-1449 are called to the attention of the Examiner for the above patent application. Copies of these documents are enclosed.

Citation of these documents shall not be construed as:

1. an admission that the documents are necessarily prior art with respect to the instant invention;
2. a representation that a search has been made, other than as described above; or
3. an admission that the information cited herein is, or is considered to be, material to patentability as defined in § 1.56(b).

EXPRESS MAIL
LABEL NO:

EL873075620US

Respectfully submitted,


James S. Hsue

Attorney for Applicants
Reg. No. 29,545

10/16/01
Date

LAW OFFICES OF
SKJERNEN MORRILL
MacPHERSON LLP

25 METRO DRIVE
SUITE 700
SAN JOSE, CA 95110
(408) 453-9200
FAX (408) 453-7979

#799521

U.S. Department of Commerce, Patent and Trademark Office					Atty Docket No.		Serial No.	
					M-10703 US		09/833,084	
INFORMATION DISCLOSURE STATEMENT BY APPLICANT					Applicant(s)			
(Use several sheets if necessary)					Ibrahim Abdulhalim et al.			
					Filing Date		Group	
					April 10, 2001			
U.S. Patent Documents								
*Examiner Initial		Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate	
	AA	4,929,083	5/29/90	Brunner			3/20/89	
	AB	5,216,257	6/1/93	Brueck et al.			7/9/90	
	AC	4,703,434	10/27/87	Brunner			4/24/84	
	AD	5,712,707	1/27/98	Ausschnitt et al.			11/20/95	
	AE	5,479,270	12/26/95	Taylor			5/19/92	
	AF	5,939,226	8/17/99	Tomimatu			1/8/97	
	AG	5,923,041	7/13/99	Cresswell et al.			4/25/95	
	AH	5,912,983	6/15/99	Hiratsuka			7/25/97	
	AI	5,902,703	5/11/99	Leroux et al.			3/27/97	
	AJ	5,872,042	2/16/99	Hsu et al.			8/22/96	
	AK	5,757,507	5/26/98	Auschnitt			11/20/95	
Foreign Patent Documents								
							Translation	
		Document	Date	Country	Class	Subclass	Yes	No
	AL							
	AM							
	AN							
	AO							
	AP							
OTHER ART (Including Author, Title, Date, Pertinent Pages, Etc.)								
	AQ	Bishoff, J. et al., "Light Diffraction Based Overlay Measurement", <i>Proceedings SPIE</i> Vol. 4344-28(2001)						
	AR	Levinson, Harry, "Lithography Process Control", <i>SPIE Press</i> Vol. TT28 Chapter 5 (1999) pps. 87-118						
	AS	Moharam, M.G. et al., "Rigorous Coupled-Wave Analysis of Planar-Grating Diffraction", <i>J. Opt. Soc. Am.</i> 73, 1105-1112 (1983)						
Examiner			Date Considered					
*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with your communication to applicant.								

U.S. Department of Commerce, Patent and Trademark Office				Atty Docket No.		Serial No.		
				M-10703 US		09/833,084		
INFORMATION DISCLOSURE STATEMENT BY APPLICANT				Applicant(s)				
(Use several sheets if necessary)				Abdulhalim, Ibrahim; Abel, Mike; Faeyman,				
				Filing Date		Group		
				April 10, 2001				
U.S. Patent Documents								
*Examiner Initial	Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate		
	AA 6,130,750	10/10/2000	Ausschnitt et al.			8/28/97		
	AB 5,783,342	7/21/98	Yamashita et al.			12/27/95		
	AC 6,023,338	2/8/2000	Bareket			7/12/96		
	AD							
	AE							
	AF							
	AG							
	AH							
	AI							
	AJ							
	AK							
Foreign Patent Documents								
							Translation	
	Document	Date	Country	Class	Subclass	Yes	No	
	AL							
	AM							
	AN							
	AO							
	AP							
OTHER ART (Including Author, Title, Date, Pertinent Pages, Etc.)								
	AQ	Sheng, P. et al., "Exact Eigenfunctions for Square Wave Gratings: Applications to Diffraction and Surface Plasmon Calculations", <i>Phys. Rev. B</i> , 2907-2916 (1982)						
	AR	Li, L., "A Modal Analysis of Lamellar Diffraction Gratings in Conical Mountings", <i>J. Mod. Opt.</i> 40, 553-573 (1993)						
	AS							
Examiner		Date Considered						
<p>*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with your communication to applicant.</p>								